



08/691434

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Docket: 0756-1551

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Continuation Application of:)
Shunpei YAMAZAKI et al.)
Based On Serial No. 08/160,909) Art Unit: 1107
Which Was Filed: December 3, 1993) Examiner: Wilczewski
For: METHOD OF FABRICATING)
SEMICONDUCTOR DEVICES)
AND APPARATUS FOR PROCESSING)
A SEMICONDUCTOR) Date: August 2, 1996

21/F
9-17-96
MRO

PRELIMINARY AMENDMENT

Honorable Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Please preliminarily amend the subject application as follows:

IN THE CLAIMS:

Please amend claim 15 as follows:

F1
15. (Amended) The apparatus of claim 8 [14] wherein said vacuum apparatus, said irradiation apparatus and said preliminary chamber can be